

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re continuation-in-part patent application of 09/569,306 filed on May 11, 2000

Cabral, Jr., et al.

Serial No.: Not Yet Assigned

Group Art Unit: Not Yet Assigned

Filing Date: Concurrently Herewith

Examiner: Unknown

For: SELF-ALIGNED SILICIDE (SALICIDE) PROCESS FOR LOW RESISTIVITY
CONTACTS TO THIN FILM SILICON-ON-INSULATOR AND BULK MOSFETS
AND FOR SHALLOW JUNCTIONS

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner of Patents
Washington, D.C. 20231

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. All of these references were either cited or submitted in parent Application No. 09/569,306 and thus copies of these references are not provided in accordance with 37 C.F.R. §1.98(d).

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

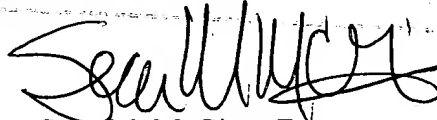
It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.



Rule 53(b) Continuation-in-part Application No. 09/569,306
filed May 11, 2000

Please charge any deficiencies in fees and credit any overpayment of fees to Assignee's
Deposit Account No. 50-0510.

Respectfully submitted,



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